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Rodney Fuller
Primary Examiner
MICRON.100C1

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

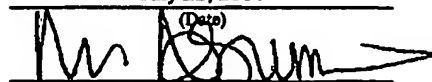
Appl. No. : 10/608,913
Applicant : Craig A. Hickman
Filed : June 26, 2003
For : DEVICE AND METHOD OF
CORRECTING EXPOSURE
DEFECTS IN
PHOTOLITHOGRAPHY
Group Art Unit : 2851
Examiner : Rodney Evan Fuller
Attny Docket No. : MICRON.100C1
Customer No. : 20,995

Confirmation No. 7050

CERTIFICATE OF FAX TRANSMISSION

I hereby certify that this correspondence and all marked attachments are being transmitted via facsimile to Examiner Rodney Evan Fuller, Fax No. 703-872-9306 of the USPTO on the date shown below:

July 22, 2004

(Date)

Mark M. Abumerl, Reg. No. 43,458

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AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

OFFICIAL

Dear Sir:

In response to the final Office Action of June 10, 2004, the Applicant submits the following amendment and remarks for consideration in connection with the above-captioned application.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.